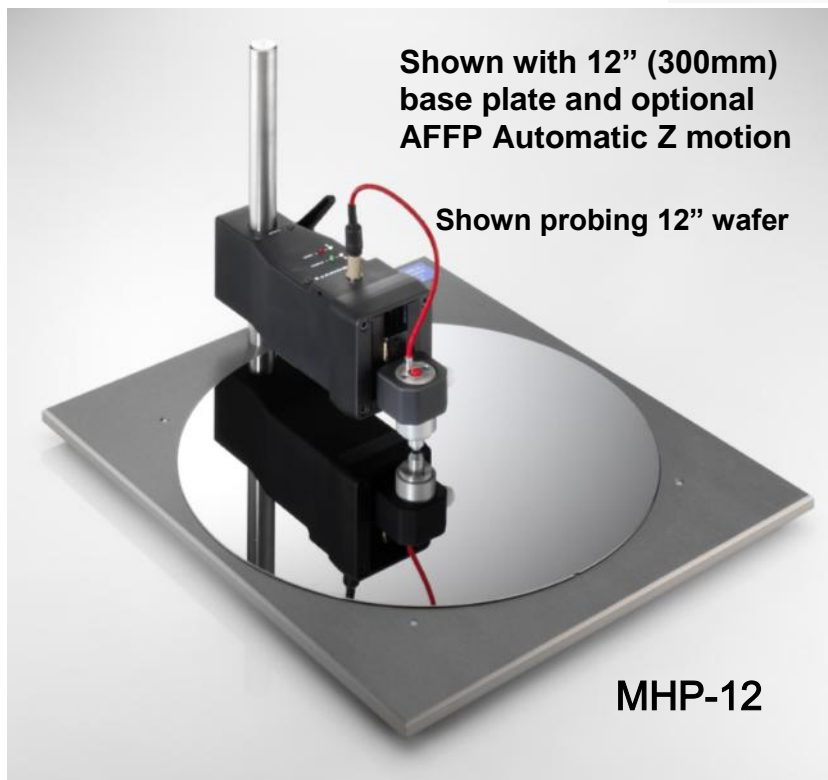
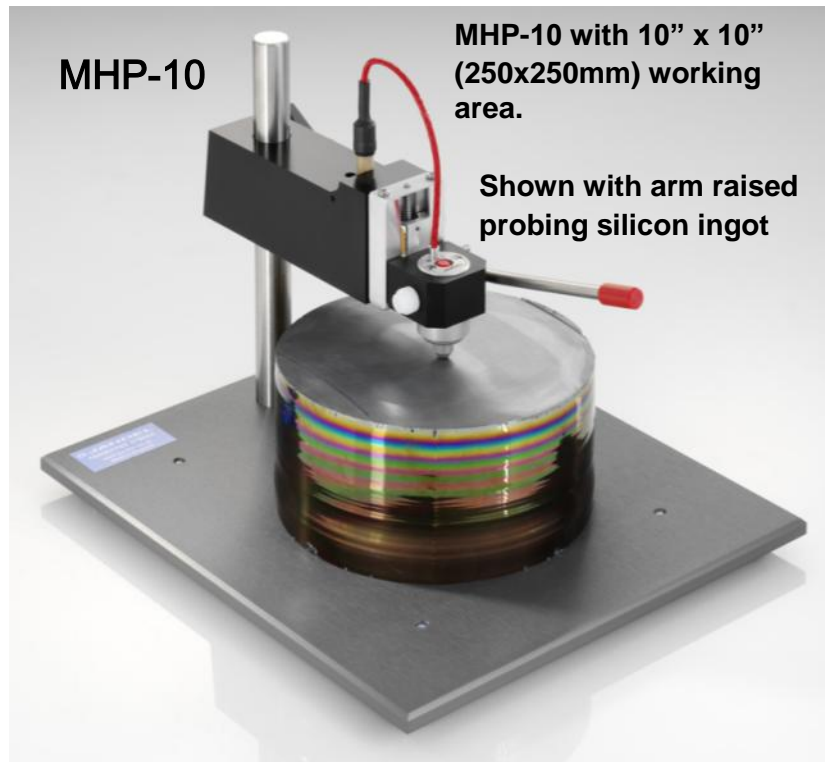


# Jandel Multi Height Probe

- Allows probing of wafers, ingots, or samples of widely varying dimensions
- Locking mechanism allows the arm to be moved up and down the steel pole and locked to suit any sample height
- Plug attached to the arm prevents the wiring from getting entangled with samples, fingers etc.
- Smooth base for positioning samples
- Includes one Jandel Cylindrical probe head
- Micro-switch prevents current from turning on until after probe head is in contact with the substrate.



- Pricing is the same for either 10" or 12" base
- Available with high temperature Cylindrical probe for use in probing with a hot plate (not supplied) at elevated temperatures. The Cylindrical probe in its standard configuration can withstand temperatures from LN2 up to 120C.
- Longer post available for probing even taller materials
- The MHP-12 version can be upgraded to add either the small sample stage (see the Multi Height Microposition Probe, or the 6" or 8" wafer stage (but without the light shield included on the regular Multi-position Wafer Probe)

# Multi Height Probe Upgrade Options

Shown with Optional  
AFPP Automatic  
Z Motion Arm

Jandel offers a 1" travel X-Y stage with a 3" diameter wafer chuck for use when positioning small samples under the probe needles. Included is the facility for vacuum hold-down. This model is available initially as the Multi Height Microposition Probe, or just the 1" travel X-Y stage with 3" vacuum chuck can be purchased as an upgrade to an existing Multi Height Probe..

It is best if Jandel knows in advance that this may be upgraded in the future so that they can provide (at no additional charge) the predrilled hole pattern. Otherwise the base plate must be returned to the factory to mount the sample stage.

Shown with Optional  
AFPP Automatic  
Z Motion Arm

Jandel offers a 6" or 8" wafer stage as an upgrade option for use with the Multi Height Probe. The wafer stage has 360° rotation with detents at each 90 degree position. User defined detents are set along the Y axis so that measurements can be made at 1, 5, 9, or more positions with 1mm location repeatability from wafer to wafer. A light shield is not built onto the system, however, Jandel offers a black cloth light shroud if required.